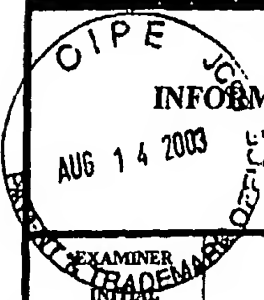


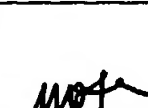
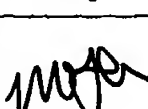
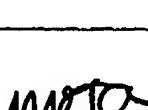
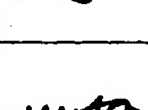
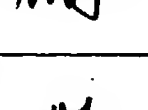

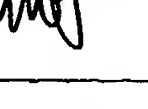
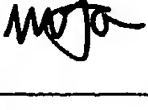
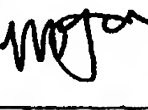
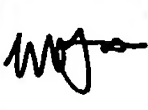
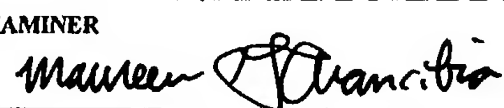


<p>OTPE</p> <p><b>INFORMATION DISCLOSURE CITATION</b></p> <p>AUG 14 2003 (Use several sheets if necessary)</p>		Docket Number (Optional)	Application Number
		FIS920020166US1	10/604,487
		Applicant(s)	
		Hendrik F. Hamann et al.	
Filing Date		Group Art Unit	
07/25/2003		1763	
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<p>*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>			

<div style="text-align: center;">  <p><b>INFORMATION DISCLOSURE CITATION</b> (Use several sheets if necessary)</p> </div>		Docket Number (Optional) <b>FIS920020166US1</b>	Application Number <b>10/604,487</b>
		Applicant(s) <b>Hendrik F. Hamann et al.</b>	
		Filing Date <b>07/25/2003</b>	Group Art Unit <b>1763</b>
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<div style="display: flex; align-items: center;"> <div style="border: 1px solid black; border-radius: 50%; padding: 5px; margin-right: 10px; text-align: center;"> OIP E AUG 14 2003 *EXAMINER TRADEMARK OFFICE </div> <div> <b>INFORMATION DISCLOSURE CITATION</b>  <i>(Use several sheets if necessary)</i> </div> </div>		Docket Number (Optional) <b>FIS920020166US1</b>	Application Number <b>10/604,487</b>
		Applicant(s) <b>Hendrik F. Hamann et al.</b>	
		Filing Date <b>07/25/2003</b>	Group Art Unit <b>1763</b>
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<i>mja</i>		1998 SRC Annual Review, Near-Field Optics for Metrology and Lithography, Research ID 438, Robert Grober, Dept. of Applied Physics, Yale University.	
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EXAMINER <i>Maureen Francis</i>		DATE CONSIDERED <i>09/13/2004</i>	
<small>*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>			

# ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

## Title of Invention

SYSTEM AND METHODS OF ALTERING A VERY SMALL  
SURFACE AREA

Application Number : 10/604,487

Confirmation Number:

First Named Applicant: Hendrik Hamann

Attorney Docket Number: FIS920020166US1

Art Unit: 1763

Examiner: MAUREEN G. ARANCIBIA

Search string: ( 4550257 or 4925139 or 5865978 or 6002471 or 4880496 or 6078055 ).pn

## US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
<del>WPA</del>	1	4550257	1985-10-29	Binnig et al.			
<del>WPA</del>	2	4925139	1990-05-15	McCord			
<del>WPA</del>	3	5865978	1999-02-02	Cohen			
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<del>WPA</del>	5	4880496	1989-11-14	Nevenzahl, et al.			
<del>WPA</del>	6	6078055	2000-06-20	Bridger, et al.			

## Signature

Examiner Name	Date
Maureen G. Arancibia	09/13/2004